

Recent Progress

- **TWEPP Proceedings:**
Minor comments received, implemented, final submission today
- **Mosaix Probe Card**
To do: Flex only Proposal draft design for MPI
planned to do this morning – postponed to prioritize Probe Card PCB/MLO design checks – everything looks ok!
- **Probe Card FPCs - PCBs**
To be followed up with CERN PCB Workshop & Antoine for breakout boards
- **Initial testing of ER2 in DSF, to be continued**
MPI machine projects for babyMOSAIX and MOSAIX well defined for pad and ER2 Wafers
ER2 Wafers received this week, contacted successfully since Monday several times
(Several lessons learned to implement in SW for safe and reliable operation of the machine)
- **SVT SW**
Improvements on the Wafer Prober software discussed with Ivan and Angelina,
Angelina has worked in the documentation / definitions – to be refined and then implemented in the next weeks

Recent Progress

The image shows the SENTO software interface for wafer inspection. The main window displays a detailed wafer map with various features and patterns. A circular inset in the top-left corner provides a magnified view of a specific area. The interface includes several toolbars and panels:

- Top Bar:** Navigation, Stepping, Vision, and Automation tabs. Status indicators for "Unsaved data!", "ER2_babyMOSAIX_Cantilever_V1_NotchW_ArrowW", "wafermap", "XY+Z", and "3555".
- Left Toolbar:** Lens (5x), Chuck-Z, Contact, Separation, Chuck, Lift Down, Center, Go Home, User Pos, and User Pos (+). Edit Mode is currently ON.
- Right Panel:**
 - Contact:** 16072.0 μm . Buttons: Set Contact, Set Home.
 - Subsites:** Add, More.
 - Offset Values:**

	Overtravel	Separation	Hover
Overtravel	30 μm		
Separation		250 μm	
Hover			50 μm
 - Advanced Settings:** (Collapsible section)
- Bottom Left:** Positioning data: X: -62830.0 μm , Y: 203671.7 μm , Z: -5694.3 μm , θ : 0.0000°.
- Bottom Right:** A vertical toolbar with icons for Off-Axis, Light, Disabled, Meas. XY, Small, AF, and Auto.
- Bottom Center:** A 500 μm scale bar.

The Windows taskbar at the bottom shows the system time as 12:24 PM on 2/17/2026.

Recent Progress

The image shows the SENTO software interface for wafer inspection. The main window displays a wafer map with a grid and various features. A circular magnification view is visible on the left side of the wafer map. The interface includes several toolbars and panels:

- Top Bar:** Contains the SENTO logo and tabs for Navigation, Stepping, Vision, and Automation. It also displays system information: Unsaved data!, ER2_babyMOSAIX_Cantilever_V1_NotchW_ArrowW, wafermap, XY+Z, and 35555.
- Left Toolbar:** Includes icons for Lens (5x), Chuck-Z, Contact, Separation, Chuck, Lift Down, Center, Go Home, User Pos, and User Pos. There is also an Edit Mode toggle (OFF/ON).
- Right Panel:** Contains a list of settings and controls:
 - Contact:** 16072.0 μm . Buttons: Set Contact, Set Home.
 - Subsites:** Add, More.
 - Offset Values:** Overtravel (30 μm), Separation (250 μm), Hover (50 μm). Each has a Set button.
 - Advanced Settings:** (Collapsible section)
- Bottom Right Panel:** Includes icons for Off-Axis, Light, Disabled, Meas. Y, Small, AF, and Auto.
- Bottom Left Panel:** Displays coordinates: X: -63226.1 μm , Y: 220628.9 μm , Z: -5694.3 μm , B: 0.0000°.
- Bottom Status Bar:** Shows system icons and the time 12:31 PM on 2/17/2026.